

PAUL SCHERRER INSTITUT



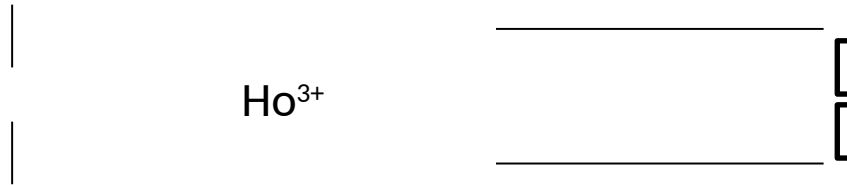
Noemi Cerboni :: PhD :: Paul Scherrer Institut

Preparation and Characterization of Holmium Sources for the HOLMES Experiment

Seminar, 12.05.2022



Goal: prepare sources for the measurement of the electron neutrino mass from the electron capture decay of ^{163}Ho



Ideal source

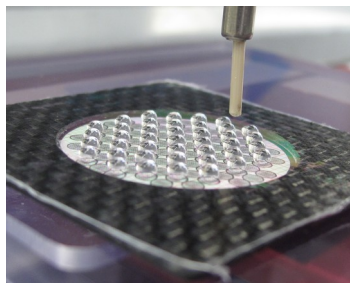
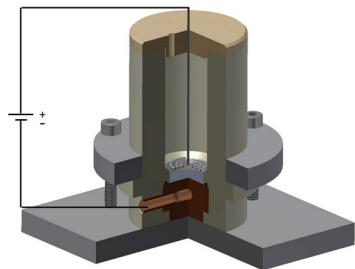
1. Chemically pure
2. Homogeneous distribution of Ho \Rightarrow slow and constant Ho release
3. Obtained with high yield

Outline

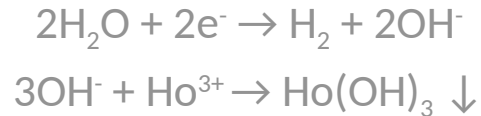
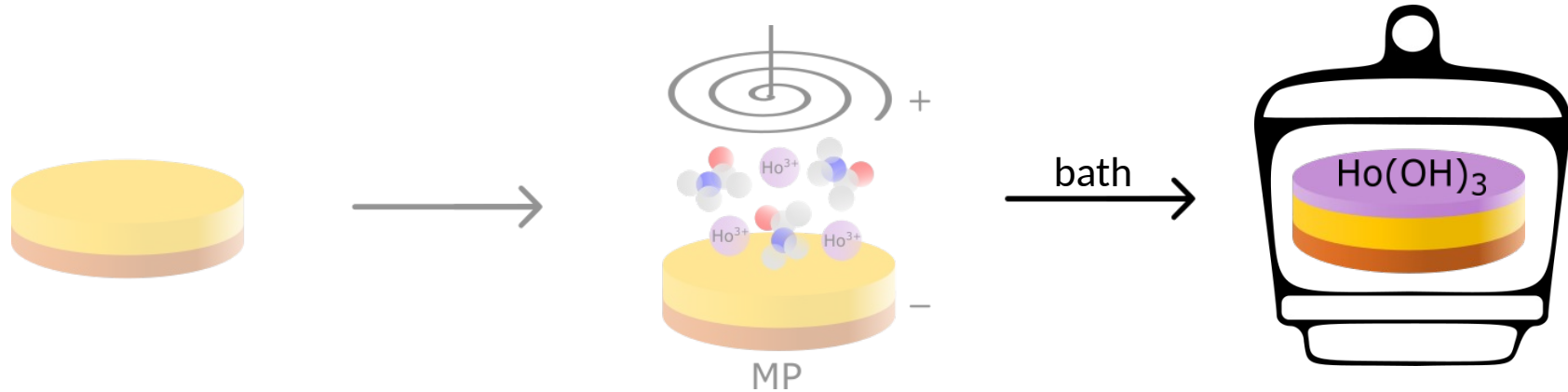
Molecular Plating
(MP)

Drop-on-Demand
Inkjet Printing
(DoD)

Coupled
Reduction (CR)



Molecular Plating (MP): deposition of Ho complexes in an organic solvent at high voltages



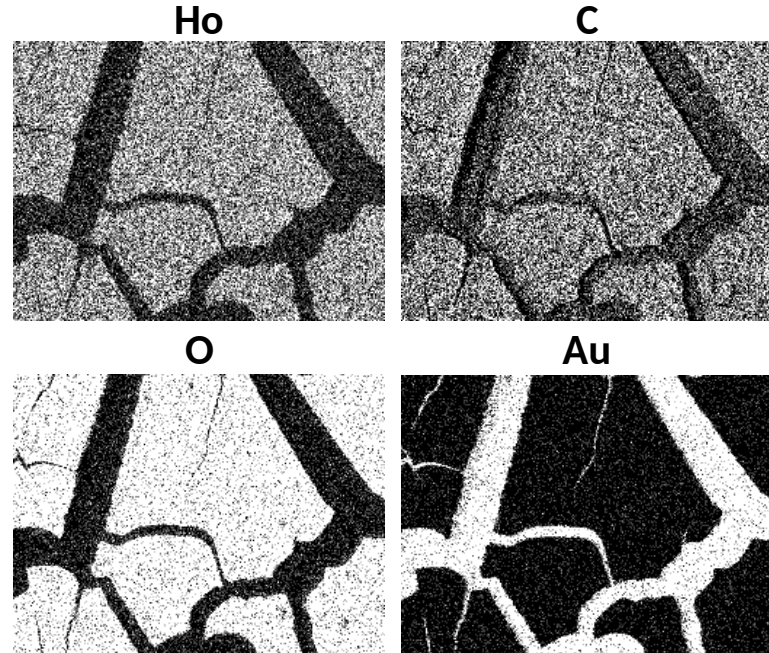
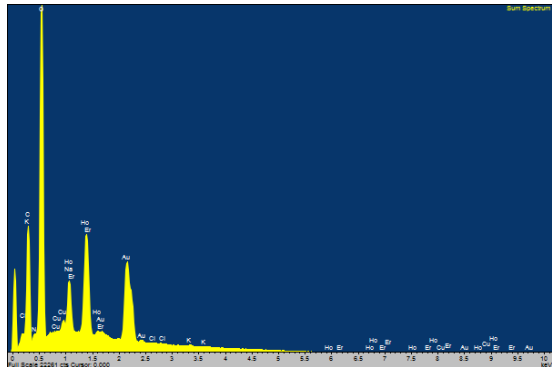
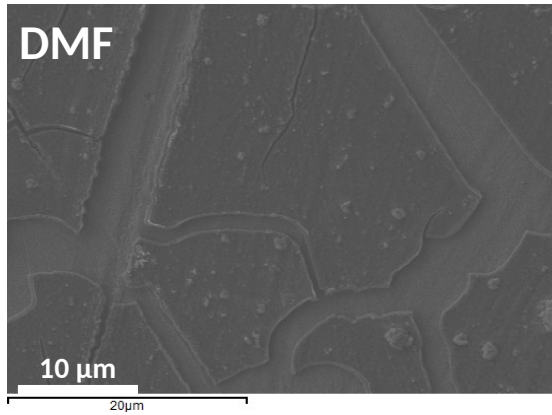
Investigation of influence of solvent's vapor pressure on morphology

Effect of Solvents on the Yields

Measured by γ -spectroscopy with ^{166m}Ho as radiotracer

solvent	MP yield (%)	Bath losses (%)
Acetone	79	0
Isobutanol	98.1	0
Isopropanol	99.9	14.8
DMF	99.4	1.8
DMAc	96.5	0

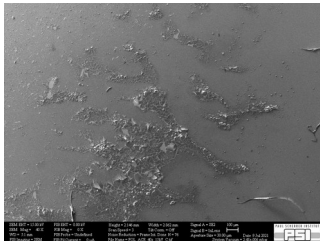
Very high yields and good adherence to backing



- Most likely deposition of $\text{Ho}(\text{OH})_3$ and co-deposition of org. compounds
- Similar chemical composition for all solvents

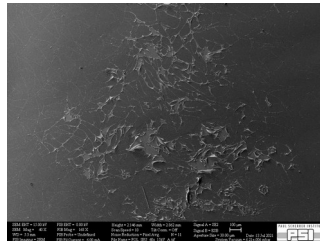
30.80 kPa

Acetone



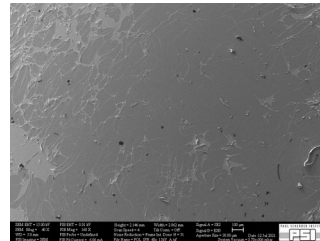
5.78 kPa

Isopropanol



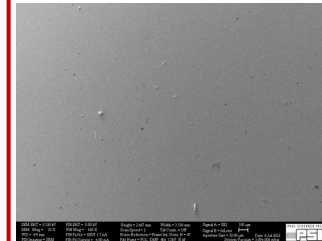
1.53 kPa

Isobutanol



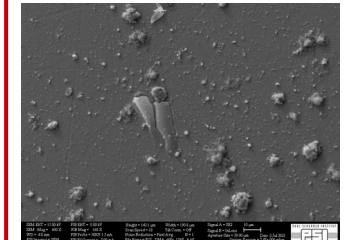
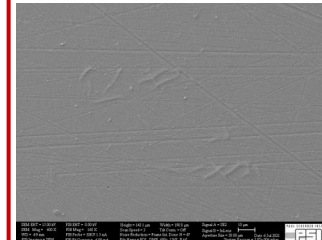
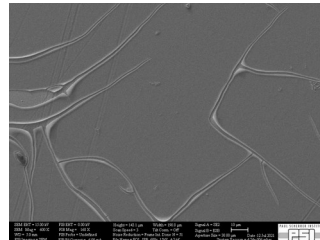
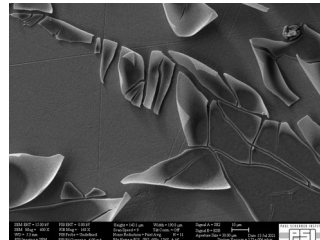
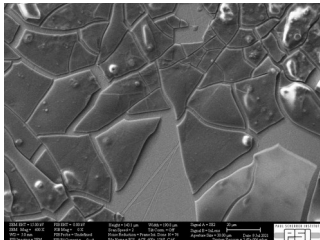
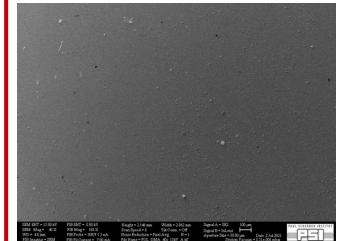
0.44 kPa

DMF



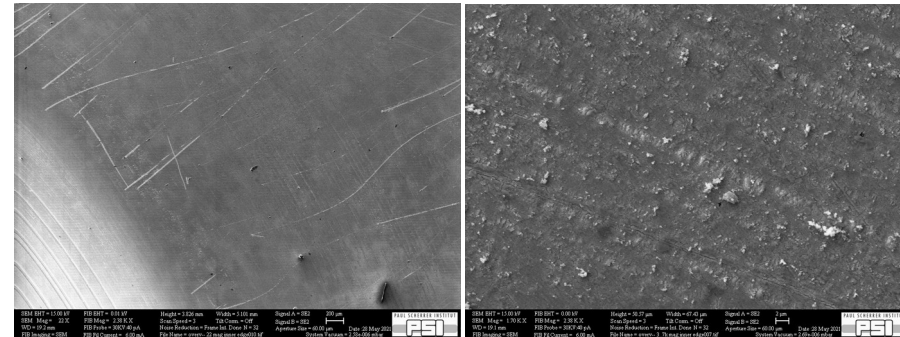
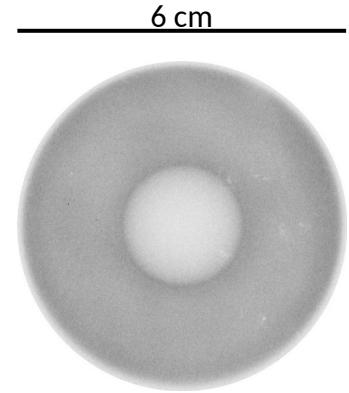
0.17 kPa

DMAc



The lower the vapour pressure the more stable the deposition (less cracks, less flaking)

- Very high yields (> 99%)
- Homogeneous deposition
- Good microstructure (similar to small samples)
- no relevant current detected at 165 u but at 182 u in mass separator \square might correspond to HoOH^+
- Very low current \square sputtering of thin film at the same time

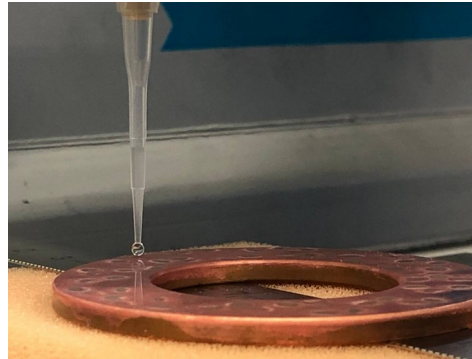


Drop-on-Demand Inkjet Printing



3D positioning system (automatic movement)

Dosage device (droplet deposition)



Deposition of droplets with identical volume (3-7 μL)

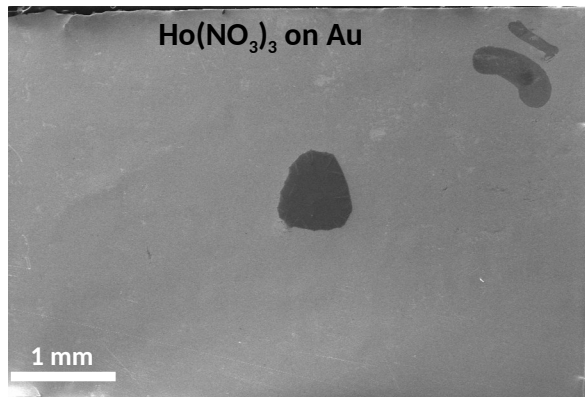
Investigate different sources produced starting from different Ho salts

SEM Imaging of Different Ho Salts on Au

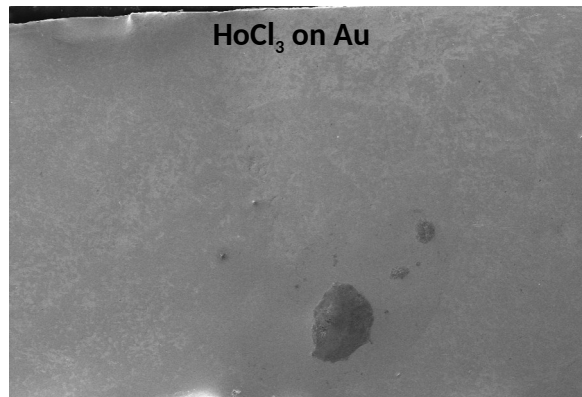
5 mm



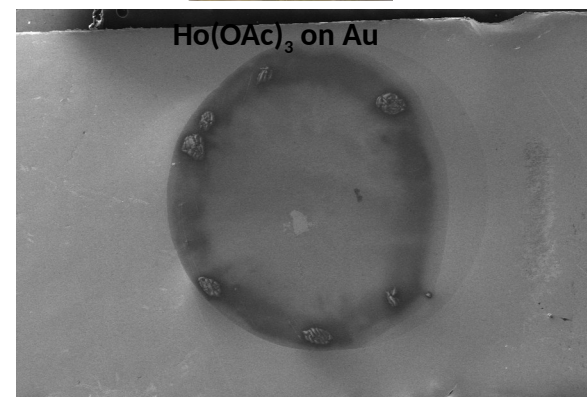
Ho(NO₃)₃ on Au



HoCl₃ on Au

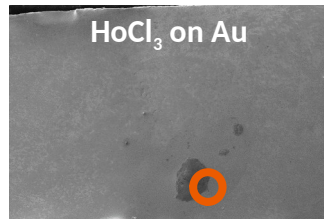


Ho(OAc)₃ on Au



- Different drying mechanism for Ho(NO₃)₃ and HoCl₃ versus Ho(OAc)₃
- In our case, more uniform deposition (and hence higher surface density) with Ho(OAc)₃

Elemental Mapping *via* EDX

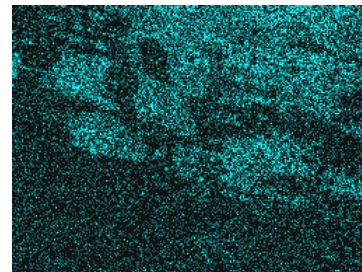
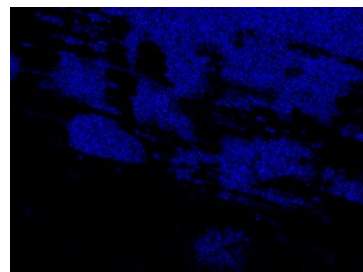
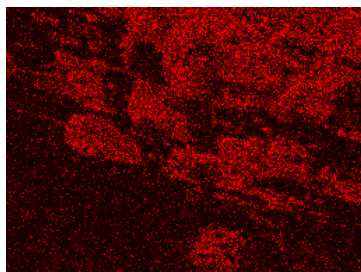
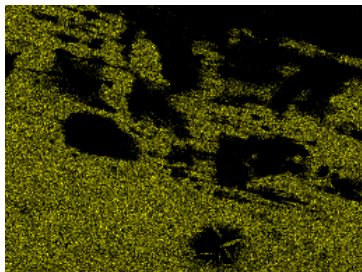
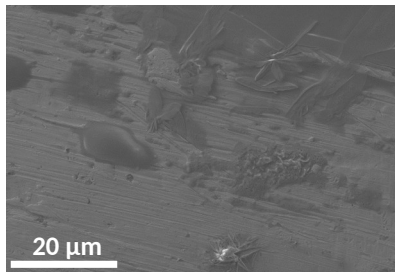


Au

Ho

O

N

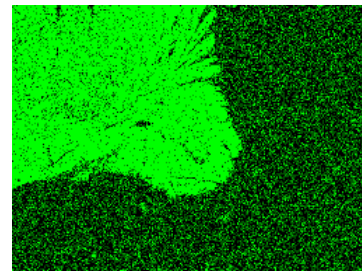
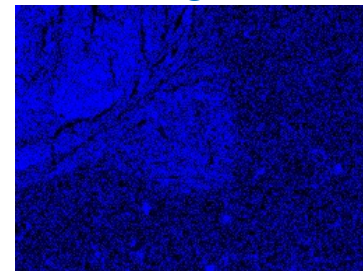
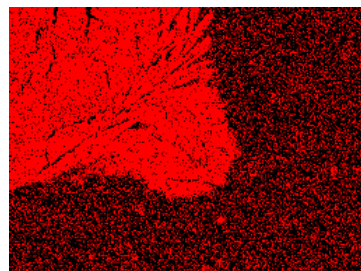
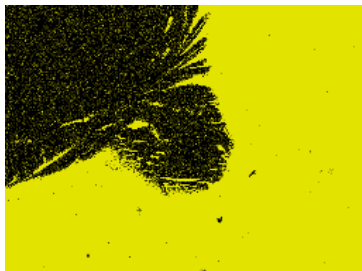
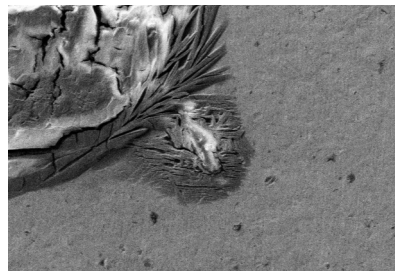


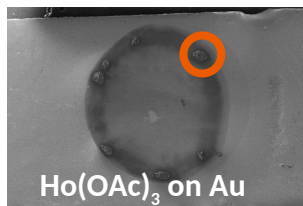
Au

Ho

O

Cl



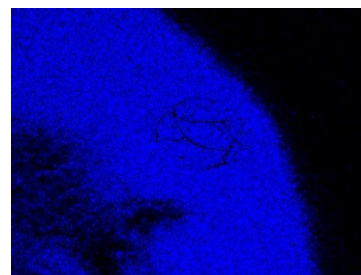
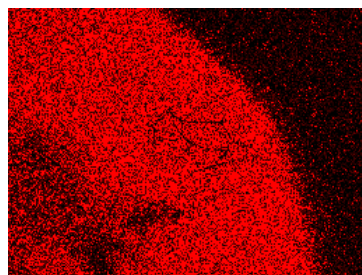
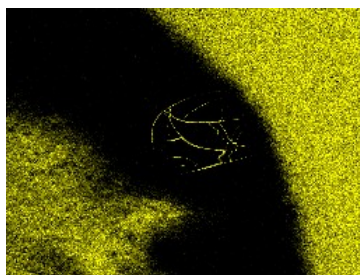
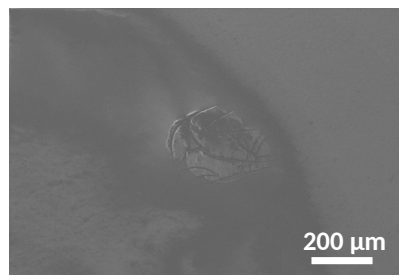
Elemental Mapping *via* EDX

Au

Ho

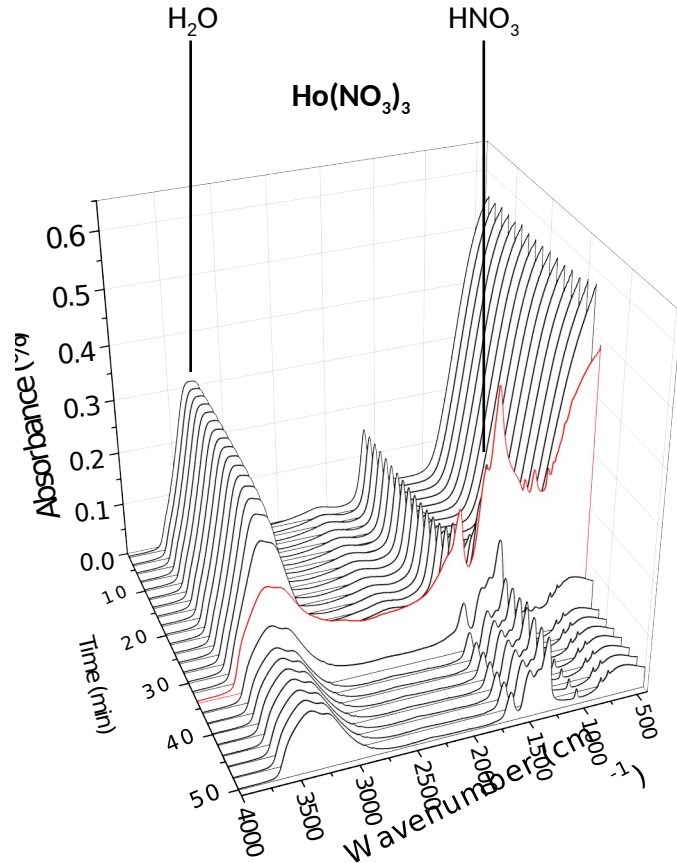
O

C

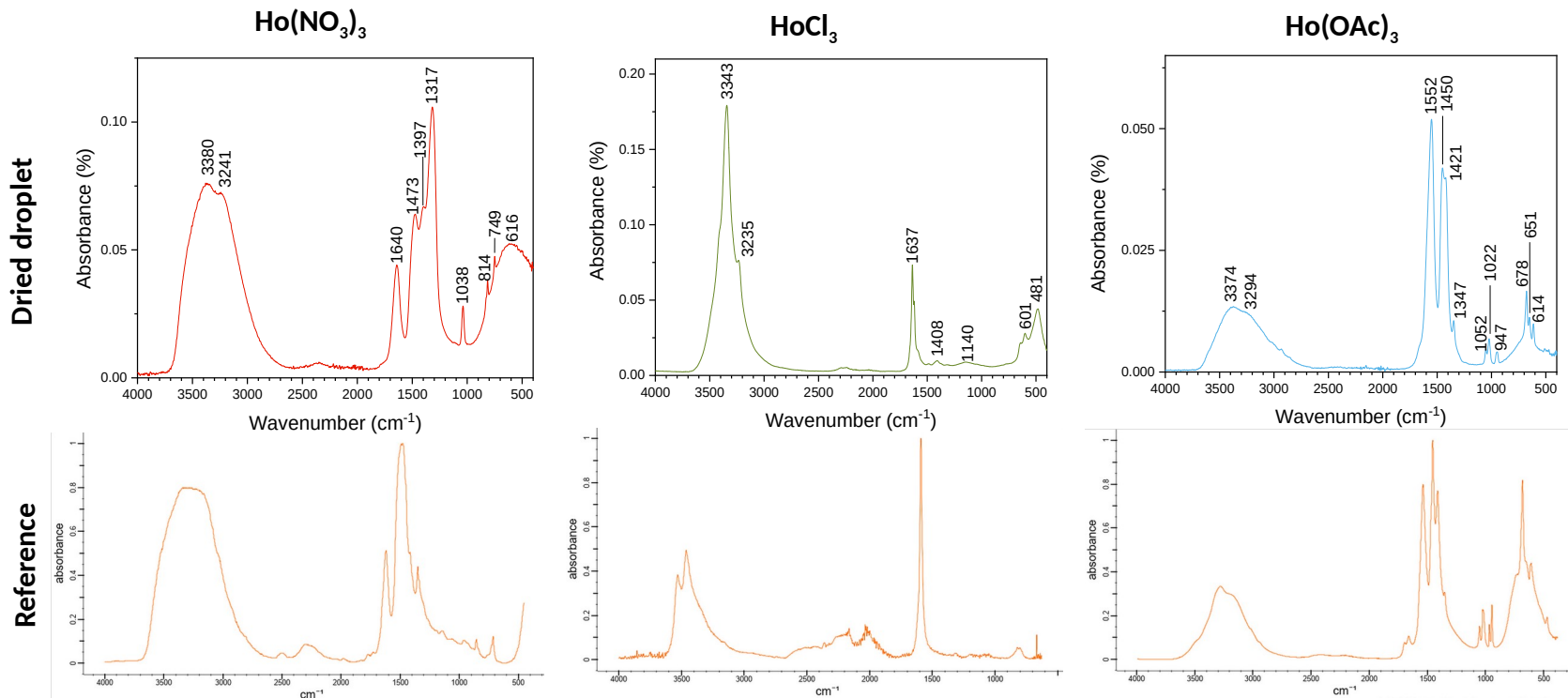


Indicate elemental composition of dried substances does not change upon drying (with unknown ratio)

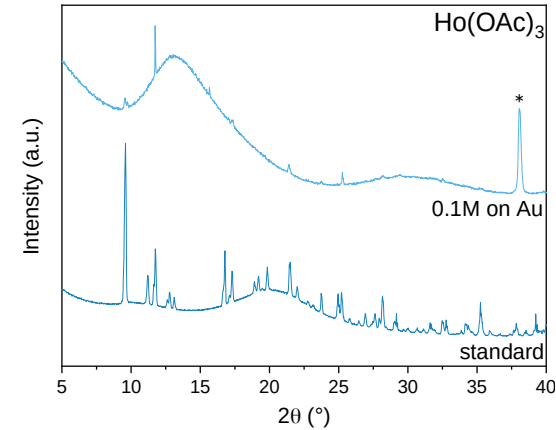
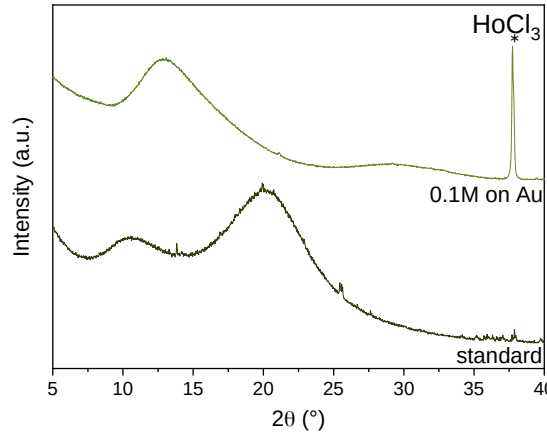
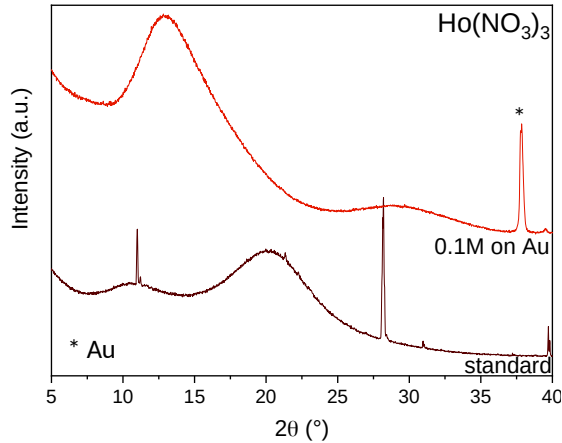
Time-Resolved Infrared Spectroscopy



- *In-situ* monitor drying mechanism: start from IR spectrum of H_2O and finish with spectrum of dried product
- Here: scan every 2 min for 1h

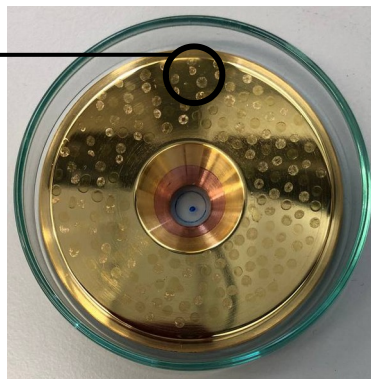
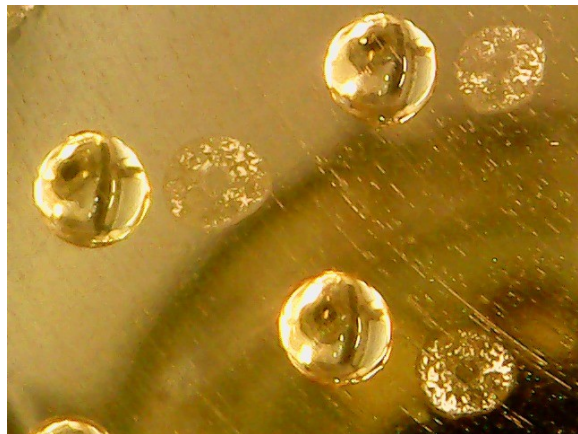


- Likely change in coordination geometry visible from change in peak intensity
- Still, dried product correspond to dissolved Ho salt



- No reflection signals in drops on substrate
 - Either deposit an amorphous material
 - or impossible detection of the actual drop
- Preferentially orientated crystallisation
- Other studies with high-intensity synchrotron radiation required (under evaluation)

Large Cathode - Results

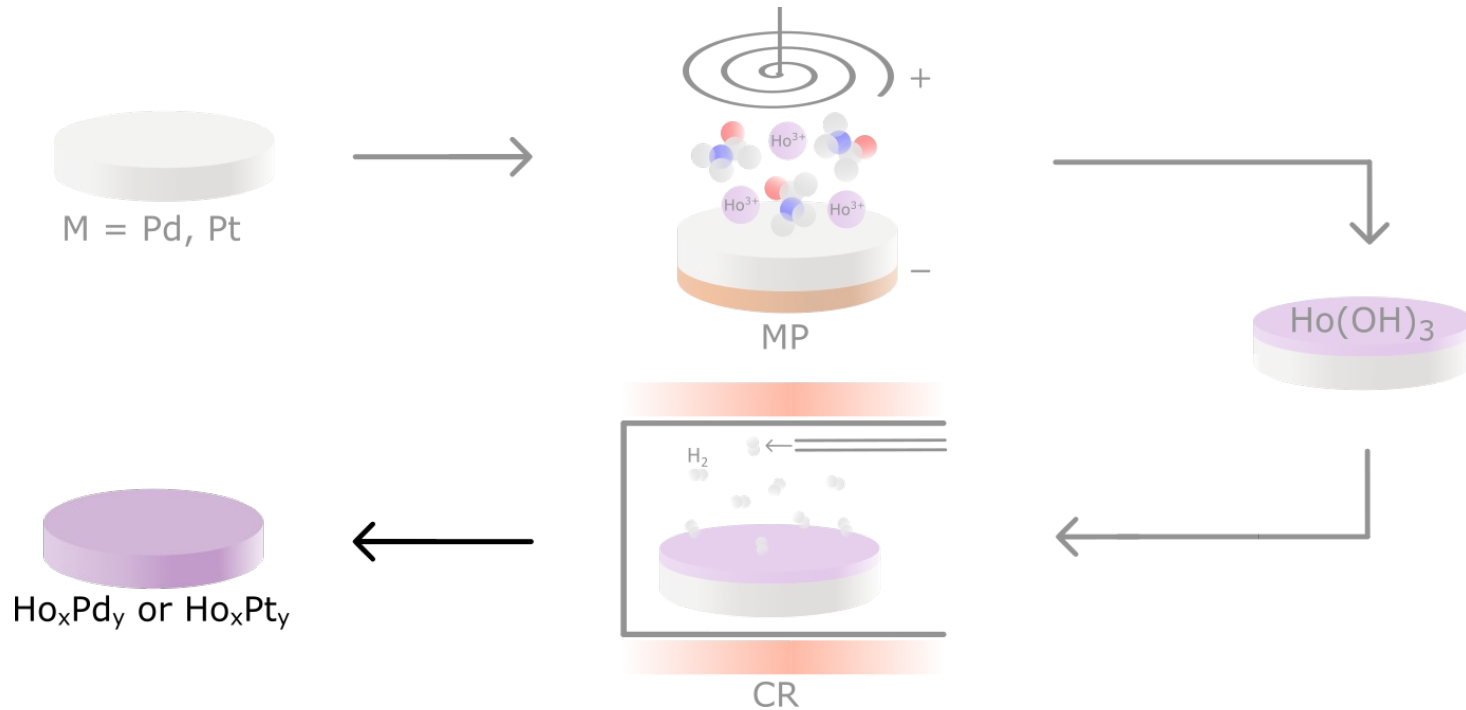


190 droplets of 3.5 μL each

Weak peak detected at 165 u but it significantly decreases over time \square too fast sputtering

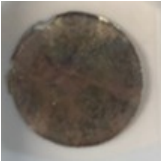

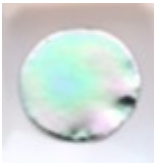

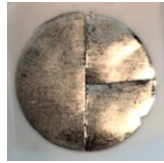

Coupled Reduction

Coupled Reduction (CR): Ho reduction and diffusion into backing material due to thermodynamically favourable formation of intermetallic compound



Study two different backing materials and different Ho concentrations

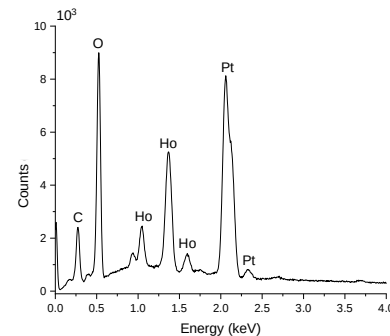
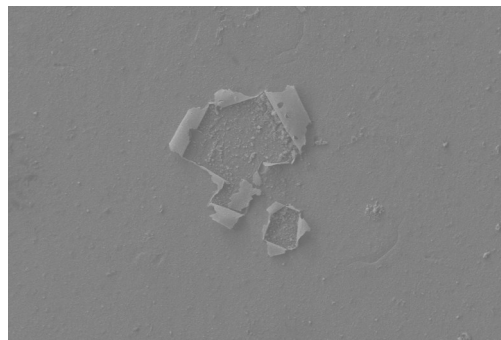
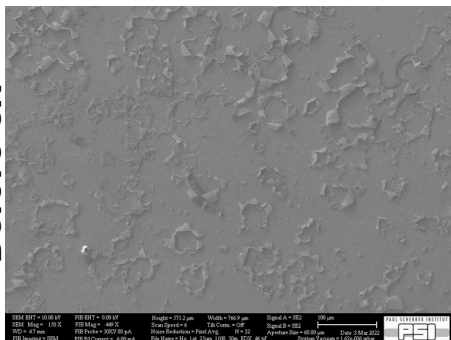
Yield of Molecular Plating

Pt		Pd			
0.25 wt%	0.25 wt%	0.5 wt%	1.25 wt%	2.5 wt%	5 wt%
99.4 %	99.6 %	99.2 %	99.2 %	92.8 %	84.9 %
					

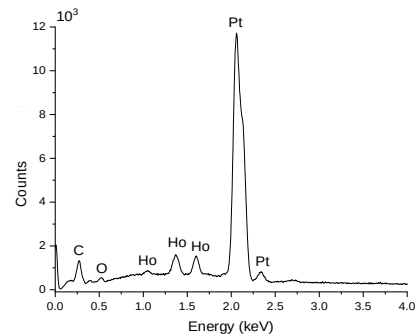
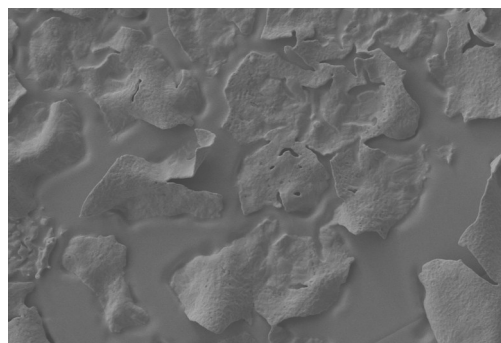
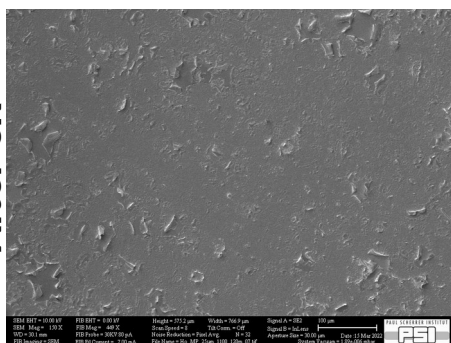
- Uniform surface distribution
 - 5 wt% Ho on Pd \Rightarrow deposited layer too thick to be stable
- Increase of thickness of deposited layer visible from color

Ho-Pt before and after CR

Before CR



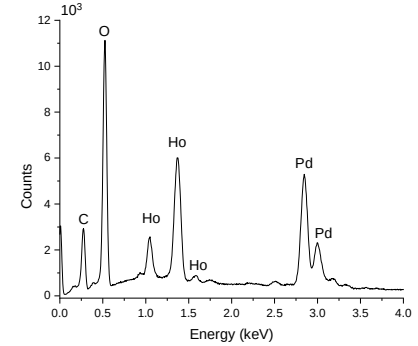
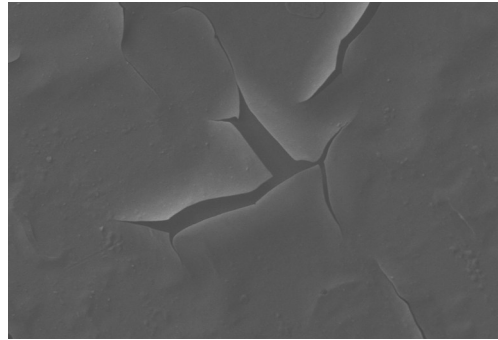
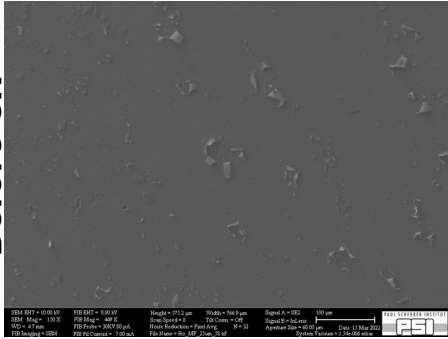
After CR



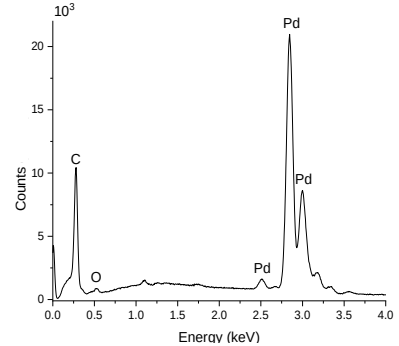
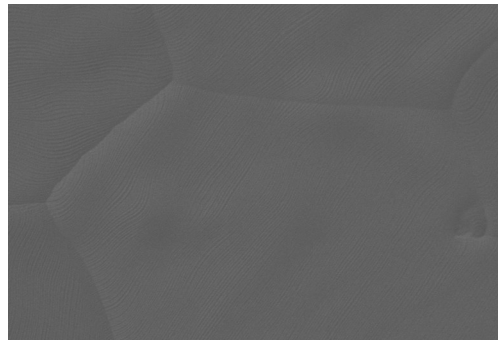
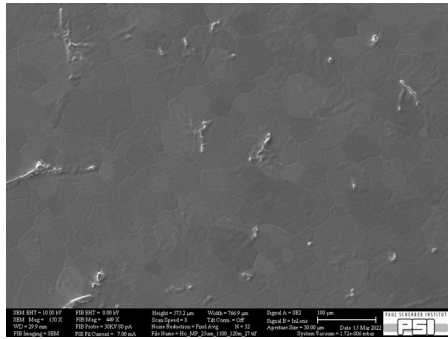
- Similar morphology as before CR \Rightarrow no Ho diffusion
- After CR: very small O peak \Rightarrow Ho reduction

Ho-Pd before and after CR

Before CR



After CR



- Grain boundaries of Pd visible \Rightarrow Ho diffusion
- After CR: no Ho and O peak \Rightarrow successful Ho reduction and diffusion

Preparation of Ho/Pd intermetallic \Rightarrow to be measured

- MP
 - Very high yields
 - Deposition of Ho complexes \Rightarrow fast sputtering of HoOH^+
- DoD:
 - Very high yields
 - Deposition of one Ho complex with labile bonds \Rightarrow fast sputtering of Ho^{x+}
- CR:
 - High yields
 - Formation of Ho^0 into the bulk of the backing material \Rightarrow constant sputtering of Ho

My thanks go to

- Emilio
- Patrick
- Dorothea
- Rugard
- Robert
- Lu
- Ivan
- Mario
- Georg
- Dominik
- ...

